

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

**SECOND SUPPLEMENTAL INFORMATION  
DISCLOSURE STATEMENT BY APPLICANT**

Atty. Docket No.  
**UBAT1510**



The PTO did not receive the following listed item(s) a check for \$180.

Applicant <b>Gregory R. Hanson et al.</b>	
Application Number <b>10/649,251</b>	Filed <b>August 26, 2003</b>
For <b>Spatial Heterodyne Interferometry for Transmission (SHIFT) Measurements</b>	
Group Art Unit <b>2877</b>	Examiner <b>Connolly, Patrick J</b>

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

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I hereby certify that this correspondence is being deposited with the U.S. Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on Aug 24, 2005.

John J. Bruckner

Applicants respectfully request, pursuant to 37 C.F.R. §§ 1.56, 1.97 and 1.98, that the art listed on the attached PTO-1449 form be considered and cited in the examination of the above-identified application. A copy of the art is enclosed for the convenience of the Examiner. Furthermore, pursuant to 37 C.F.R. §§ 1.97(g) and (h), no representation is made that a search has been made or that this art is material to patentability of the present application. Copies of the non-US patent references are enclosed for the convenience of the Examiner.

This Information Disclosure Statement is being filed after mailing of a First Office Action. Applicant hereby requests consideration of this Information Disclosure Statement pursuant to 37 C.F.R. § 1.97(c)(2). A check in the amount of \$180 representing the fee set forth in 37 CFR § 1.17(p) is enclosed.

While Applicants believe no (further) fees are due, if any (further) fees are due, the Commissioner is hereby authorized to charge any fees or credit any overpayments to Deposit Account No. 50-3204 of John Bruckner PC.

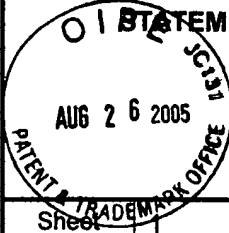
Dated: Aug 24, '05

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Respectfully submitted,  
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INFORMATION DISCLOSURE STATEMENT BY APPLICANT			Application Number		10/649,251	
			Filing Date		August 26, 2003	
			First Named Inventor		Gregory R. Hanson	
			Group Art Unit		2877	
			Examiner Name		Connolly, Patrick J	
Sheet 1 of 1		Attorney Docket		UBAT1510		
<b>U.S. PATENT DOCUMENTS</b>						
Examiner Initials	Cite No.	Document Number		Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	
		Number	Kind Code (if known)			
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		6,809,845	B1	10/26/2004	Kim et al.	
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Examiner Initials	Cite No.	<b>FOREIGN PATENT DOCUMENTS</b>		Publication Date MM-DD-YYYY (Number 43)	Name of Patentee or Applicant of Cited Document	
		Country Code	Number			
		JP	06282213		07/10/1994 Citizen Watch Co. Ltd.	
Examiner Signature				Date Considered		

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### NON-PATENT LITERATURE DOCUMENTS

Examiner Initials	Cite No.	Citation
		Invention of Holography: D. Gabor, Proc. Roy. Soc. London Ser. A <u>A197</u> , 459 (1949).
		Invention of Sideband (Hetrodyne) Holography: E. Leith and J. Upatnieks, J. Opt. Soc. Am. <u>52</u> , 1123 (1962) and J. Opt. Soc. Am. <u>53</u> 1377 (1963).
		Mathematical Treatise on Holography: J.B. Develis and G.O. Reynolds, Theory and Application of Holography, Addison-Wesley, Reading, MA, 1967.
		Holographic Interferometry: L.O. Heflinger, R.F. Wuerker, and R.E. Brooks, J. Appl. Phys. <u>37</u> , 642 (1966).
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		Interferogram Analysis: Digital Fringe Pattern Measurement Techniques, M. Kujawinska, (edited by D.W. Robinson and G.T. Reid), IOP Publishing Ltd., Bristol, England, 1993).
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Examiner Signature		Date Considered

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<b>Examiner Initials</b>	<b>Cite No.</b>	<b>Citation</b>			
		Volkl, E., et al. "Advanced Electron Holography: A New Algorithm for Image Processing and Standardized Quality Test for the FEG Electron Microscope", ULTRAMICROSCOPY 58 (1995) 97-103.			
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<b>Examiner Signature</b>				<b>Date Considered</b>	